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## SIMULATION OF DISTRIBUTION OF ELECTROPHYSICAL PARAMETERS OVER A CHROMIUM COMPENSATED GALLIUM ARSENIDE WAFERS\*

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The paper presents the results of simulation and experimental studies of resistivity and charge carrier lifetimes distribution over chromium-compensated gallium arsenide (HR GaAs:Cr) wafers, made of n-GaAs wafers by means of high-temperature diffusion of chromium.

It has been demonstrated that the inhomogeneity of resistivity and charge carrier lifetime distribution is determined, in particular, by the inhomogeneity of the donor impurity in n-GaAs wafers.

Analysis of the research results allows to conclude:

- application of a four-level model, including deep and shallow acceptors and donors, makes it possible to qualitatively and quantitatively evaluate and predict the characteristics of the HR GaAs:Cr material and sensors based on it;
- the best qualitative and quantitative agreement between the calculated and experimental values of nonequilibrium charge carrier lifetimes, Hall mobility and resistivity in HR GaAs:Cr wafers are achieved when using EL2 center concentration in the range  $(1-3)\times10^{15}$  cm<sup>-3</sup>, Cr concentration about  $1\times10^{17}$  cm<sup>-3</sup> and concentrations of thermal acceptors in the range of  $(1-4)\times10^{16}$  cm<sup>-3</sup>;
- the lifetime of nonequilibrium electrons and holes is determined by the concentration of ionized EL2+ centers and Cr- ions, respectively.

## **REFERENCES**

- [1] F. A. Silva, "Energy Efficient Computing and Electronics: Devices to Systems [Book News]", IEEE Industrial Electronics Magazine, vol. 14, no. 1, pp. 100-101, 2020, doi: 10.1109/MIE.2020.2966835.
- [2] I. Chsherbakov, I. Kolesnikova, A. Lozinskaya, T. Mihaylov, V. Novikov, A. Shemeryankina, O. Tolbanov, A. Tyazhev and A. Zarubin, "Electron mobility-lifetime and resistivity mapping of GaAs:Cr wafers", Journal of Instrumentation, vol.12, no. C02016, 2017 doi: 10.1088/1748-0221/12/02/C02016.
- [3] E. Hamann, "Characterization of high resistivity GaAs as sensor material for photon counting semiconductor pixel detectors: PhD Thesis", 2013.
- [4] D. Budnitsky, V. Novikov, A. Lozinskaya, I. Kolesnikova, A. Zarubin, A. Shemeryankina, T. Mikhailov, M. Skakunov, O. Tolbanov and A. Tyazhev, "Characterization of 4 inch GaAs:Cr wafers", Journal of Instrumentation, vol.12, no. P. C01063, 2017, doi: 10.1088/1748-0221/12/01/C01063.
- [5] E.M. Omelyanovsky, V.I. Fistul, Impurities of transition metals in semiconductors, Moscow: Metallurgy, 1983.
- [6] W.V. Machado, E.C Cipriano and M.A. Amato, "Experimental Evidence of Deep Acceptor levels in GaAs Exposed to Near Band Gap Light", Brazilian Journal of Physics, vol. 27/A, no. 4, Dec.1997.

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